

EL465855441

Inventor: **Vladimir S gal et al.**

Title: **Methods of Forming Aluminum-Comprising Physical Vapor
Deposition Targets; Sputtered Films; and Target
Constructions**

Assignee: **Honeywell International Inc.**

Serial No.: **Filed herewith**

Filing Dt.: **Filed herewith**

Honeywell Docket No.: **30-5022(4015)**



INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

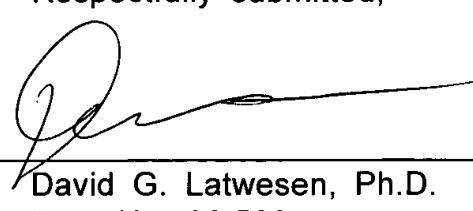
In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, the Examiner's attention is directed to the references listed on the attached Form PTO-1449 and copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,

Date: 2/13/01

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